



501.30598CC3

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): MORIOKA, et al
Serial No.: 09/805,188
Filed: March 14, 2001
For: METHOD AND APPARATUS FOR ANALYZING THE STATE
OF GENERATION OF FOREIGN PARTICLES IN
SEMICONDUCTOR FABRICATION PROCESS
Group: 2877
Examiner: T. Nguyen

AMENDMENT AFTER FINAL ACTION

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 23, 2004

Sir:

In response to the Office Action September 23, 2003, the following amendments and remarks are respectfully submitted in connection with the above-identified application, as listed below and as set forth on the following pages:

Amendment of the Claims; and

Remarks are included following the amendments.

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